



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Hidetoshi Nishiyama, et al.

Application No.: 09/931,997

Filed: 08/17/2001

For: METHOD AND ITS APPARATUS
FOR INSPECTING PARTICLES OR
DEFECTS OF A SEMICONDUCTOR
DEVICE

Customer No.: 20350

Confirmation No.: 4181

Examiner: K. K. Pyo

Technology Center/Art Unit: 2878

RESPONSE TO RESTRICTION
REQUIREMENT

and

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Counsel for Assignee elects the species of Figures 11-14 (claims 14-16) for prosecution.

Prior to examination of the above-referenced application, please enter the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.

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